

Patent Assignment Abstract of Title

Total Assignments: 1

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Issue Dt:

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Inventors: Chao-Cheng Chen, Jen-Cheng Liu, Jyu-Horng Shieh

Title: Method for preventing photoresist poisoning

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Exec Dt: 08/22/2001

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Exec Dt: 08/22/2001

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Search Results as of: 4/3/2003 11:04:22 A.M.

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L Number	Hits	Search Text	DB	Time stamp
1	339256	darc or arc	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/04/03 10:57
2	438	((darc or arc) with ((titanium adj nitride) or (metal adj nitride)))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/04/03 11:49
3	174	((darc or arc) with ((titanium adj nitride) or (metal adj nitride))) and photoresist	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/04/03 11:59
4	29	((((darc or arc) with ((titanium adj nitride) or (metal adj nitride))) and photoresist) and damascene\$2	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/04/03 11:59
5	79	((darc or arc) with ((tantalum adj nitride) or (metal adj nitride)))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/04/03 11:56
6	73	((darc or arc) with ((tantalum adj nitride) or (metal adj nitride))) not (((darc or arc) with ((titanium adj nitride) or (metal adj nitride))) and photoresist)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/04/03 11:57
7	8	((((darc or arc) with ((tantalum adj nitride) or (metal adj nitride))) not (((darc or arc) with ((titanium adj nitride) or (metal adj nitride))) and photoresist)) and damascene\$2	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/04/03 11:57
8	58	((darc or arc) with ((tugsten adj nitride) or (metal adj nitride)))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/04/03 11:58
9	53	((darc or arc) with ((tugsten adj nitride) or (metal adj nitride))) not (((darc or arc) with ((titanium adj nitride) or (metal adj nitride))) and photoresist)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/04/03 11:57
10	1	((((darc or arc) with ((tugsten adj nitride) or (metal adj nitride))) not (((darc or arc) with ((titanium adj nitride) or (metal adj nitride))) and photoresist)) and damascene\$2	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/04/03 11:57
11	1922	((darc or arc) with (tan or tin or (metal adj nitride)))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/04/03 11:58
12	238	((darc or arc) with (tan or tin or (metal adj nitride))) and photoresist	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/04/03 11:59

13	27	(((darc or arc) with (tan or tin or (metal adj nitride))) and photoresist) and damascene\$2	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/04/03 11:59
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